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Docket No.: 50090-334

**PATENT****IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of :

Masanobu IWASAKI, et al. :

Serial No.: 09/934,474 :

Group Art Unit: 3723

Filed: August 23, 2001 :

Examiner: H. Shakeri

For: POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING POLISHING  
SOLUTION, APPARATUS FOR AND METHOD OF POLISHING SEMICONDUCTOR  
SUBSTRATE AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

**PETITION FOR EXTENSION OF TIME**

Commissioner for Patents  
Washington, DC 20231

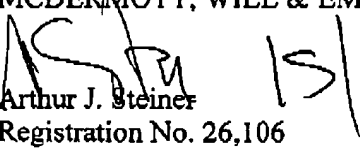
Sir:

It is respectfully requested that the time for response to the Office Action dated April 18, 2002, now due to expire July 18, 2002, be extended for two months and set to expire on September 18, 2002.

Please charge the extension fee of \$400.00 to Deposit Account No. 500417. Please charge any additional fees or credit any overpayment to Deposit Account No. 500417.

Respectfully submitted,

MCDERMOTT, WILL &amp; EMERY



Arthur J. Steiner

Registration No. 26,106

07/12/2005 LWASHING 00000004 500417 09934474

01 FC:1252

410.00 DA  
600 13<sup>th</sup> Street, N.W.  
Washington, DC 20005-3096  
(202)756-8000 AJS/lrd  
Facsimile: (202)756-8087  
Date: September 4, 2002